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Printed Microsensors and Applications

Guest Editor:

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Deadline for manuscript submissions:

closed (31 October 2023)

Message from the Guest Editor

Dear Colleagues,

Additive manufacturing and 3D printing technologies have recently demonstrated numerous improvements and innovations in making microsensors and microelectronics. Thus, it opens a new path of manufacturing for devices that previously were difficult to build, enabling, in addition, a wide array of applications in the fields of microsensors, microelectronics, and other nano and micro devices, among others. In addition, additive manufacturing reduces the cost by 10-100x as compared to conventional fabrication.

In the last few years, the printing processes improved significantly; however, advancements are constantly being made in materials used, manufacturing processes, and applications that may be displayed.

Therefore, this Special Issue mainly focuses on the printing technologies for microsensors, microelectronics and their applications in various industries.

Prof. Dr. Ahmed Busnaina Guest Editor













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Message from the Editor-in-Chief

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